Chapter 5 Overheads

John D. Cressler, Silicon Earth: Introduction to the Microelectronics and Nanotechnology Revolution, Cambridge University Press, 2009 (© Copyright 2009, All Rights Reserved)
### Chapter 5 Overheads

<table>
<thead>
<tr>
<th>Type of Etch</th>
<th>Sidewall Profile</th>
<th>Diagram</th>
</tr>
</thead>
<tbody>
<tr>
<td>Wet Etch</td>
<td>Isotropic</td>
<td><img src="image" alt="Diagram" /></td>
</tr>
<tr>
<td>Dry Etch</td>
<td>Isotropic (depending on equipment and parameters)</td>
<td><img src="image" alt="Diagram" /></td>
</tr>
<tr>
<td></td>
<td>Anisotropic (depending on equipment and parameters)</td>
<td><img src="image" alt="Diagram" /></td>
</tr>
<tr>
<td></td>
<td>Anisotropic—Taper</td>
<td><img src="image" alt="Diagram" /></td>
</tr>
<tr>
<td></td>
<td>Silicon Trench</td>
<td><img src="image" alt="Diagram" /></td>
</tr>
</tbody>
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